Special Issue

Emerging Trends in Artificial Intelligence and Machine Learning for Advanced Collaborative Manufacturing Systems

Message from the Guest Editors

The Specisl Issue "Emerging Trends in Artificial Intelligence and Machine Learning for Advanced Collaborative Manufacturing Systems" is online! This Special Issue aims to serve as a platform for researchers and practitioners to showcase cutting-edge developments, applications, and advancements in the use of AI and ML in manufacturing applications. By showcasing innovative research and case studies, this issue seeks to emphasize how these technologies are shaping the future of manufacturing.

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